## WHAT IS CLAIMED IS:

- 1. An electronic element including:
- a substrate;
- an electrode pad on the substrate;
- a base electrode on the electrode pad;
- an intermediate electrode on the base electrode; and
- a bump electrode on the intermediate electrode;

wherein said base electrode includes a metallic material that reduces orientation of the intermediate electrode.

- 2. The electronic element of claim 1, wherein said bump electrode is made of a metal having a melting point of about 450°C or more.
- 3. The electronic element of claim 1, wherein said intermediate electrode is made of at least one of AI and an alloy including AI.
- 4. The electronic element of claim 1, wherein said base electrodes have a metallic material that increases the half-width of a locking curve of a X-ray diffraction peak from a (111) plane of AI in said intermediate electrode to more than about 15 degrees.
- 5. The electronic element of claim 1, wherein said intermediate electrode has a thickness of about 1 micrometer.
- 6. The electronic element of claim 1, wherein said base electrode has a thickness of about 10 nanometer.
- 7. The electronic element of claim 1, wherein said base electrode is made of NiCr.

8. A surface acoustic wave element, comprising:

a piezoelectric substrate;

electrode pads on the piezoelectric substrate;

intermediate electrodes including base electrodes disposed on a bottom surface of said intermediate electrodes, the bottom surface of said intermediate electrodes being disposed on said electrode pads; and

bump electrodes on the intermediate electrodes, said bump electrodes made of a metal having a melting point of about 450°C or more;

wherein said base electrodes include a metallic material that reduces orientation of the intermediate electrodes.

- 9. The surface acoustic wave element according to claim 8, wherein each of the intermediate electrodes has a plurality of layers, and between each layer of said intermediate electrodes includes said base electrodes having said metallic material that reduces orientation of said intermediate electrodes.
- 10. The surface acoustic wave element according to claim 8, wherein the intermediate electrodes are made of at least one of Al and an alloy including Al.
- 11. The surface acoustic wave element according to claim 10, wherein the base electrodes include a metallic material that increases the half-width of a locking curve of a X-ray diffraction peak from a (111) plane of Al in said intermediate electrodes to be more than about 15 degrees.
- 12. The surface acoustic wave element according to claim 8, wherein the base electrodes comprise NiCr.
- 13. The surface acoustic wave element according to claim 8, wherein the electrode pads comprise AI or an alloy including AI.

- 14. The surface acoustic wave element according to claim 8, further comprising a package having package electrodes, said bump electrodes bonded to said package electrodes.
- 15. The surface acoustic wave element according to claim 14, further comprising a cap arranged to seal said package airtight.
  - 16. A method of manufacturing an electronic element, comprising the steps of: providing a piezoelectric substrate;

forming electrode pads on the piezoelectric substrate;

disposing intermediate electrodes on the electrode pads, said intermediate electrodes including base electrodes located between said electrode pads and said intermediate electrodes;

forming bump electrodes on the intermediate electrodes;

disposing the electronic element on a package such that said bump electrodes opposes package electrodes; and

press-bonding said package electrodes to said bump electrodes while applying ultrasonic waves or heat;

wherein said base electrodes include a metallic material that reduces orientation of the intermediate electrodes.

- 17. The method of claim 16, further comprising sealing the package airtight with a cap.
- 18. The method of claim 16, further comprising providing intermediate electrodes having a plurality of layers, and disposing said base electrodes between said layers of said intermediate electrodes.
- 19. The method of claim 16, wherein said bump electrodes are made of a metal having a melting point of about 450°C or more.

20. The method of claim 16, wherein said intermediate electrode is made of at least one of AI and an alloy including AI.

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